

Supplementary Material

Algorithm 1 Mesh Cloning via Euclidean Osmosis

Input: · mesh $\mathcal{M}_1$, patch $ROI \subset \mathcal{M}_1$,
 · mesh $\mathcal{M}_2$, patch $P \subseteq \mathcal{M}_2$,
Output: · cloned mesh $\mathcal{M}^*$.
Parameters: · $tol > 0$, $k_{max} \in \mathbb{N}$
Preliminary set up:
 S1) Alignment and scaling of ROI and P ,
 S2) Construct X_{ROI} and X_P for ROI and P on $\Omega = [0, 1]^2$
 S3) Construct the triangulation $\overline{ROI}^\Omega = (\bar{V}, E, T)$
Osmotic flow between u_{ROI} and u_P :
 - Compute and apply offset m , if necessary
 - Compute u_{ROI} and u_P as in (14)
 - Compute partition of $\overline{ROI}^\Omega$ as in (15)
 - Set drift term $\mathbf{d}$ as in (16) and initialize u^0 as in (17)
 while $(\|u^{k+1} - u^k\|_2 / \|u^k\|_2 > tol)$ and $(k < k_{max})$
 $u^{k+1} \leftarrow Pu^k$ via (EXP) or (IMP) scheme
 end
 - Set $ROI^* = (u^{k+1} - m, E, T)$
 - Set $\mathcal{M}^* = (\mathcal{M}_1 \setminus ROI) \cup ROI^*$

Algorithm 2 Mesh Inpainting via NCC Osmosis

Input: · damaged mesh $\mathcal{M}_1$,
Output: · repaired mesh $\mathcal{M}^* = (V^*, E^*, T^*)$
Parameters: · $tol > 0$, $k_{max} \in \mathbb{N}$
Preliminary set up:
 S1) Generate $\overline{\mathcal{M}} = (V, E, T)$, with corrupted region $ROI \subset \overline{\mathcal{M}}$, closing holes in $\mathcal{M}_1$ (if necessary)
 S2) Compute δ_N , the NCC of the mesh $\overline{\mathcal{M}}$
Osmotic flow:
 - Compute and apply offset m , if necessary
 - Set reference function u_R as in (18)
 - Set the drift term $\mathbf{d}$ as in (19) and initialize $u^0 = u_R$
 while $(\|u^{k+1} - u^k\|_2 / \|u^k\|_2 > tol)$ and $(k < k_{max})$
 $u^{k+1} \leftarrow Pu^k$ via (EXP) or (IMP) scheme;
 end
 - Set $\delta^* = u^{k+1} + m$
 - Solve (3) for V^*
 - Set $\mathcal{M}^* = (V^*, E, T)$.
